

HVR - CCPD

STMicroelectronics chips

ATLAS ITK Italy meeting, 14/03/2016

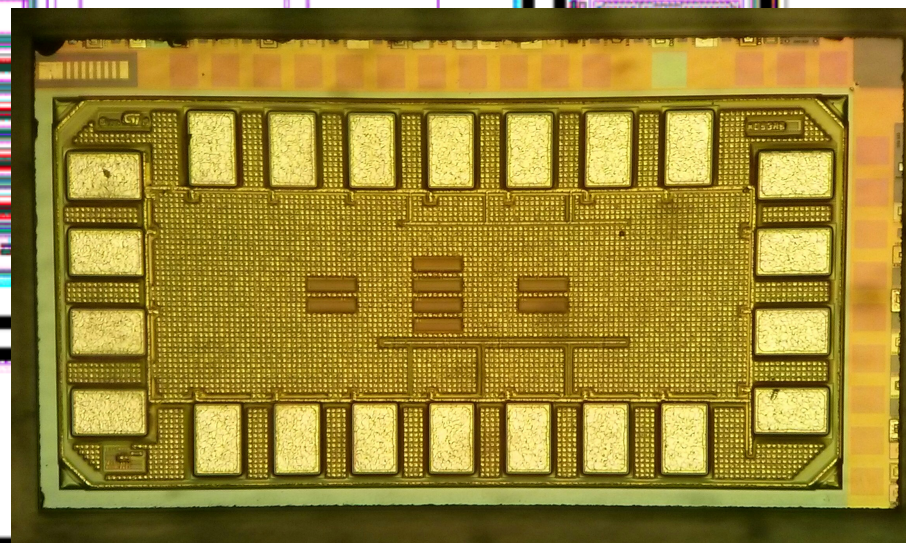
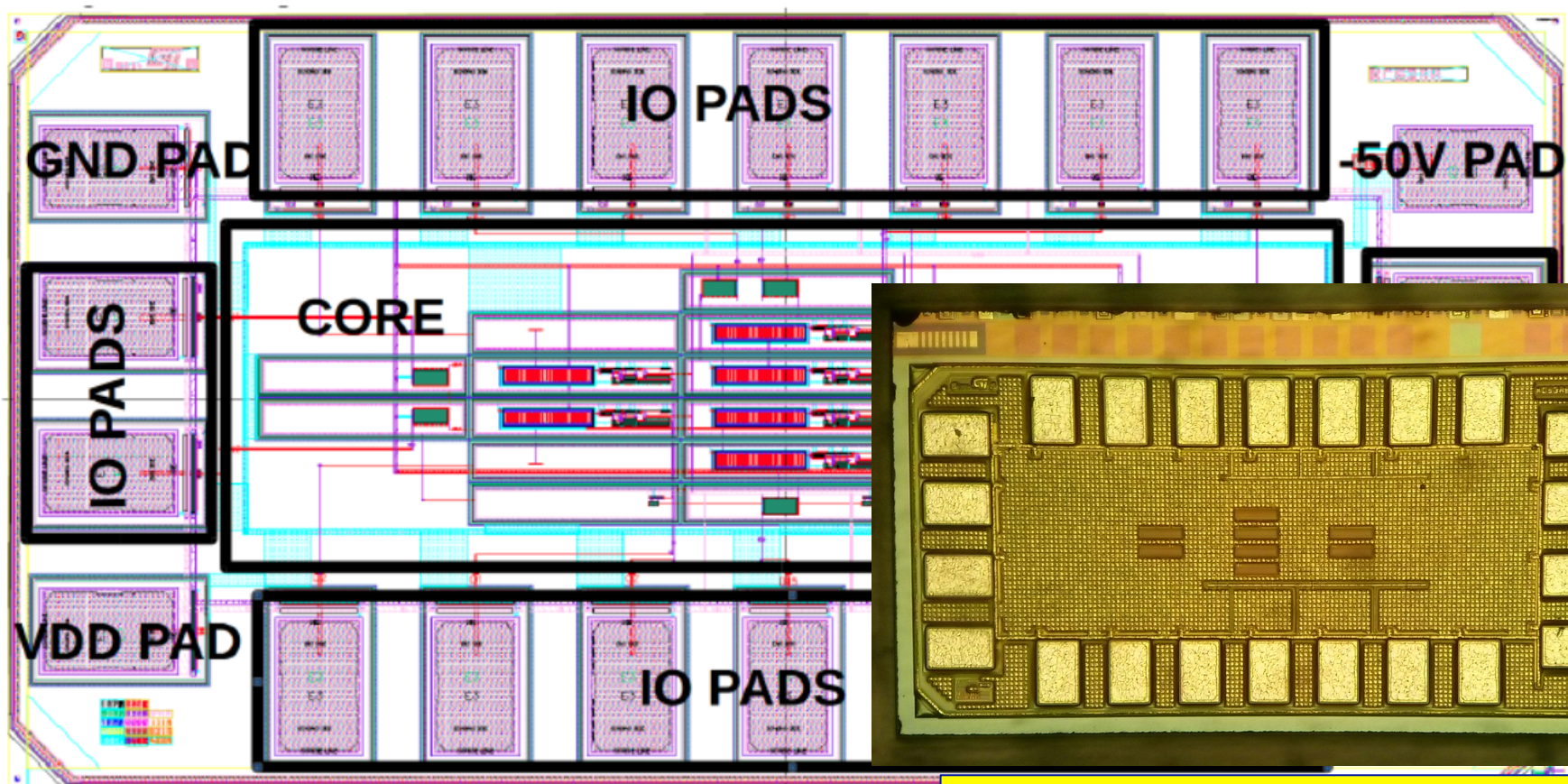
Attilio Andreazza, M. Citterio, V. Liberali, C. Meroni, F. Ragusa, E. Zaffaroni - INFN Milano

M. Biasotti, G. Darbo, G. Gariano, A. Gaudiello, C. Gemme, P. Morettini, L. Rossi, E. Ruscino, M. Sannino – INFN Genova

C. Sbarra, A. Sidoti, F. Fabbri – INFN Bologna

H. Shrimali, I. Yadav, A. Yoshi – IIT Mandi

- Reminder of passive diode performance
- Test of active pixels
 - amplifier design
 - injection circuitry
 - performance
- Submission of $3 \times 4 \text{ mm}^2$ array
 - STM postponed submission time to 22nd April
 - **Hybridization in Andrea's talk today**
 - **Simulation covered in Federica's talk tomorrow**



Layout of the STM test chip (KC53A):

- 22 I/O and VDD/GND pads
- 8 pixels ($50 \times 250 \mu\text{m}^2$): Collecting diode + Amp.
- 4 pixels ($50 \times 250 \mu\text{m}^2$): Collecting diode only

First version delivered July 2015:

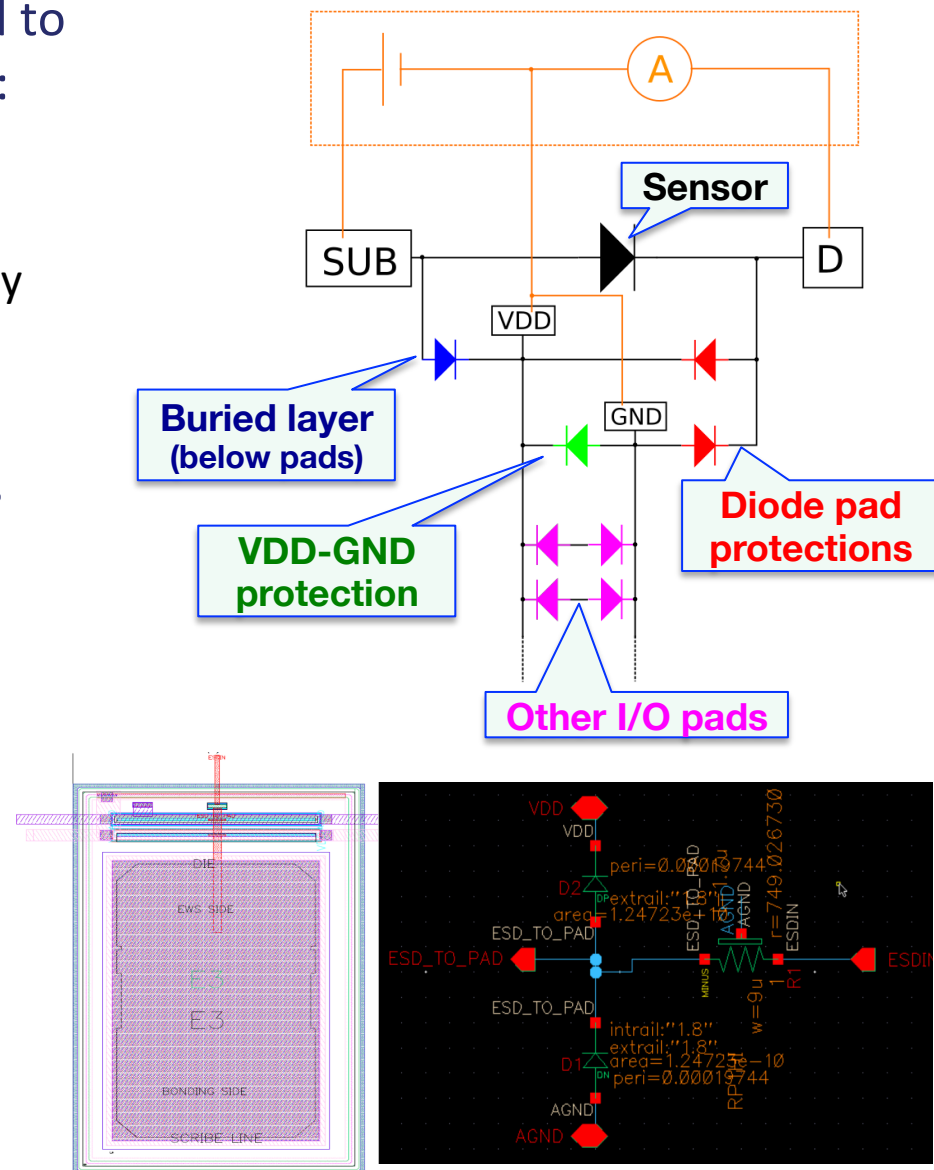
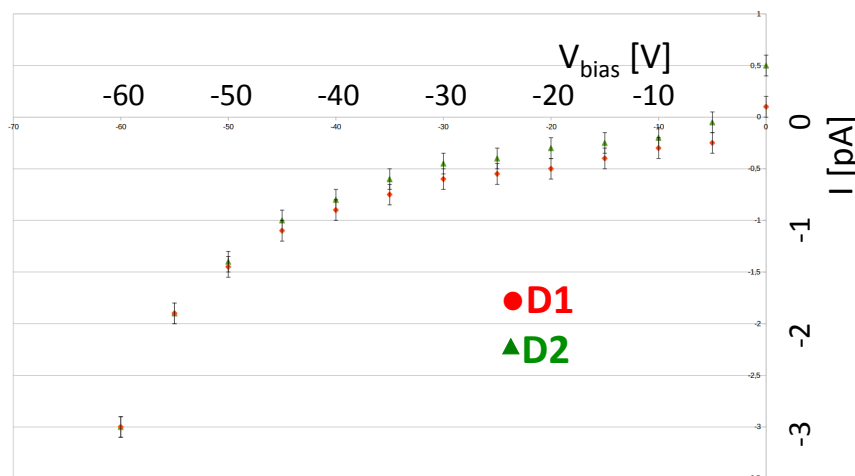
- shorts between power lines and ground

Fixed version delivered 29 Jan. 16

Design and layout by:

➤ H. Shrimali and V. Liberali (MI)

- I-V measurements (and C-V as well) need to keep into account ESD protection diodes:
 - 0.8-1.4 pA leakage current @ 50 V on $50 \times 250 \mu\text{m}^2$ pixels
 - whole chip leakage current, dominated by buried layer below I/O pads
- “Programmed” break-down at 70 V.
- STM would like us to set also protections between SUB and GND (multiple 7V breakdown structures)



- Measured capacitance parameterized as:

$$C = C_p + \frac{1}{\sqrt{k(V + V_o)}}$$

- C_p : parasitic capacitance
- V_o : built-in voltage

$$k = \frac{\mu \rho}{2 \epsilon A^2}$$

$\mu(\text{holes}) = 450 \text{ cm}^2 \text{ V}^{-1}$
 $\rho = 125 \Omega \text{ cm}$
 $\epsilon = 1 \text{ pF/cm}$
 $A = 250 \cdot 50 \mu \text{ m}^2$

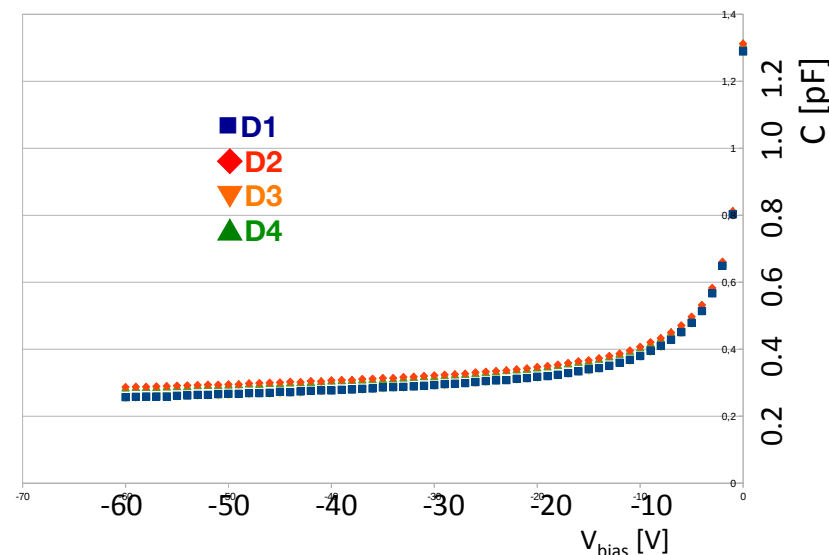
Substrate datasheet:
100-150 $\Omega \text{ cm}$

- Measurement compatible with expectation: $k = 1.8 \text{ V}^{-1} \text{ pF}^{-2}$
- Corresponding depletion is 22-24 $\mu \text{ m}$ at 50 V

$$Q = e A d N_A$$

$$V = e N_A d^2 / 2 \epsilon$$

$$C = \frac{Q}{V} = \frac{2 \epsilon A}{d}$$

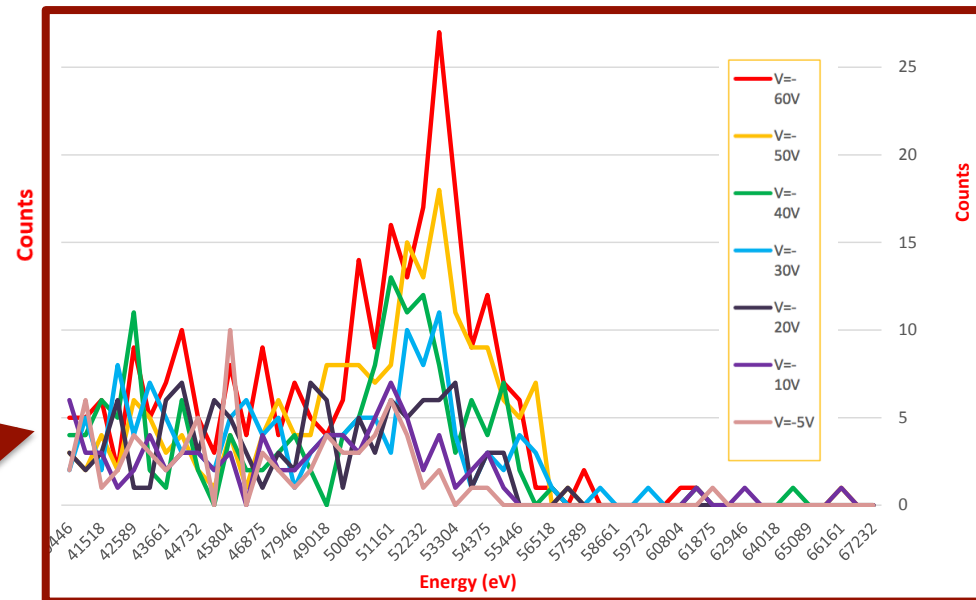
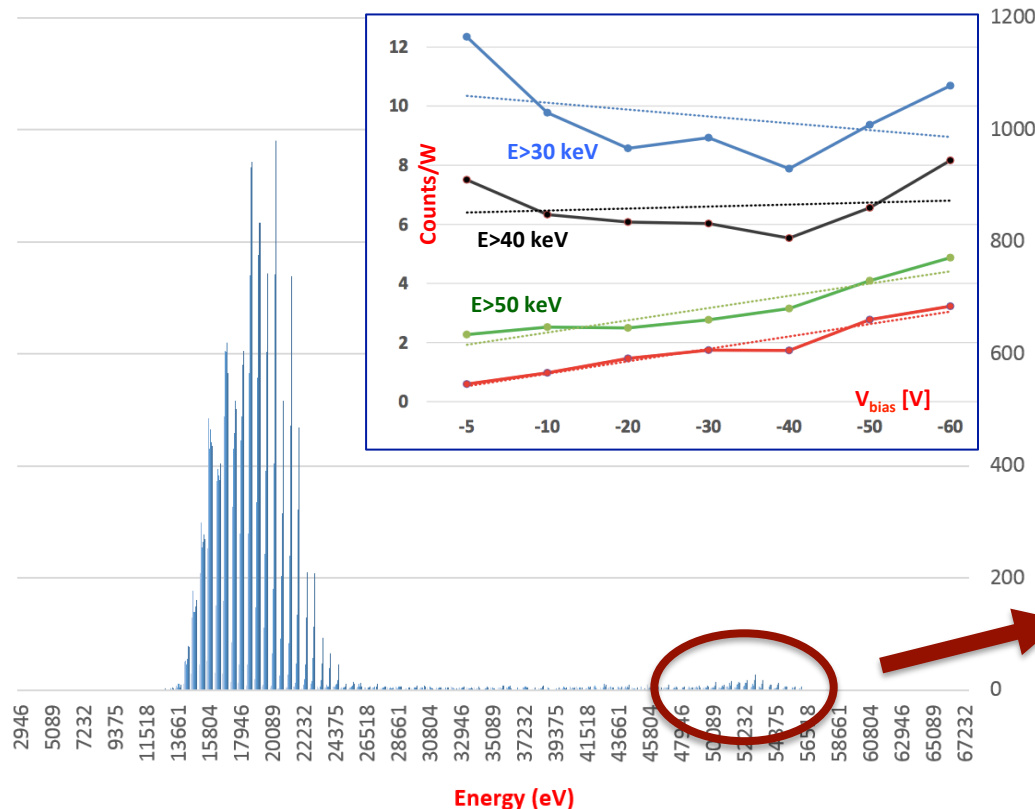


	D1	D2	D3	D4
Cp (pF)	0,156	0,191	0,153	0,191
k	1,76	1,95	1,75	1,94
Vo (V)	0,439	0,407	0,442	0,406
C-Cp@-50V (pF)	0,111	0,104	0,110	0,104

Output pads 0.12-0.15 pF

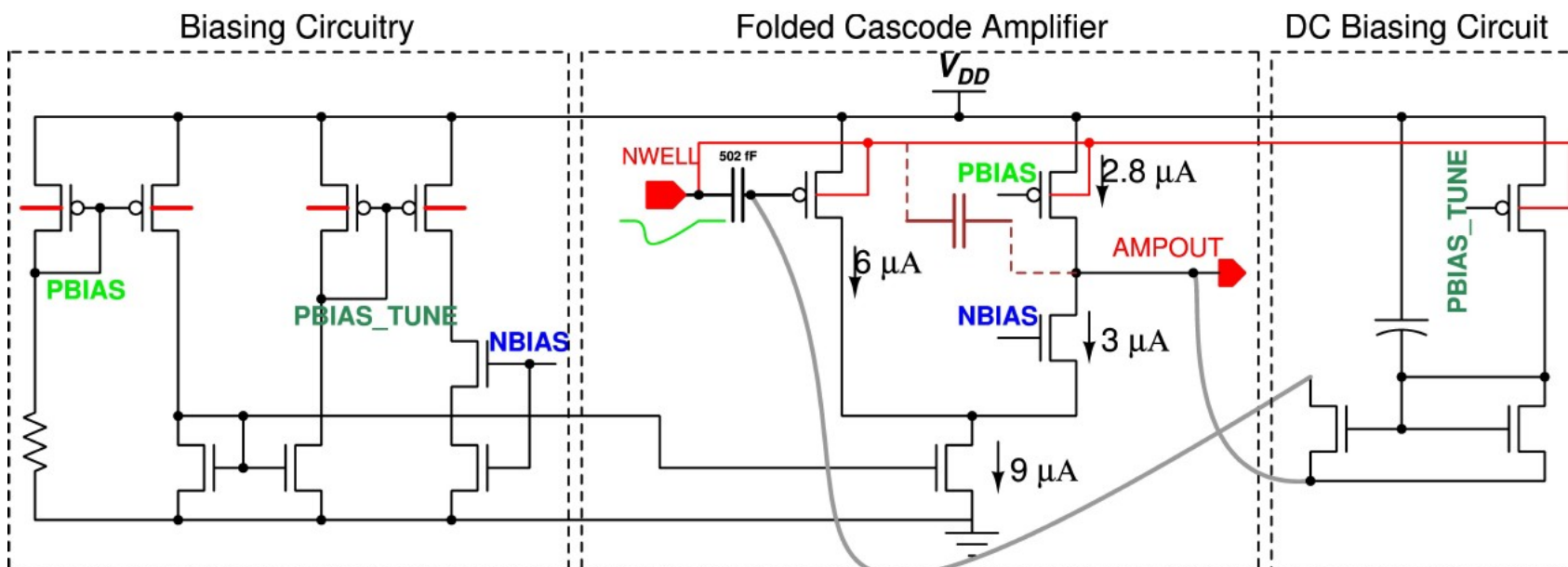
Passive diodes: source tests

- Cross check rate with ^{241}Am source
- Low rate due to small active volume
 - photoelectric peak at ~ 0.1 Hz rate with 1 mCi source
 - rate proportional to depletion (as expected)
 - peak shape dependent on depletion (range of 60 keV electron in Si $\sim 33 \mu\text{m}$)

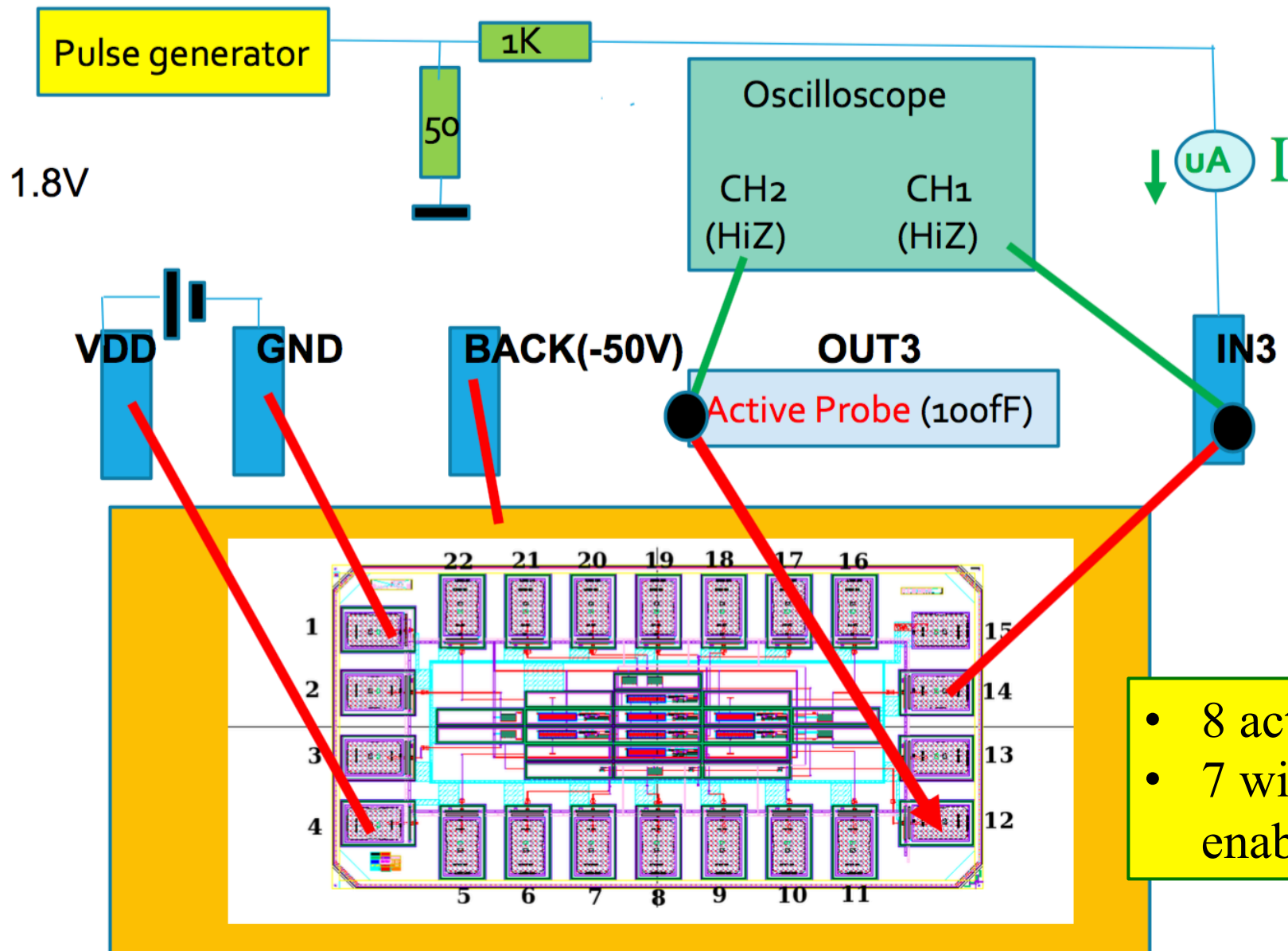


Active pixels: power consumption

- Current absorption: 0.28 mA ($V_{DD}=1.8$ V)
- corresponds to 35 μ A pixel
- in agreement with expectation from the device simulation:
 - 9 μ A for the amplifier
 - 25 μ A for the biasing circuitry



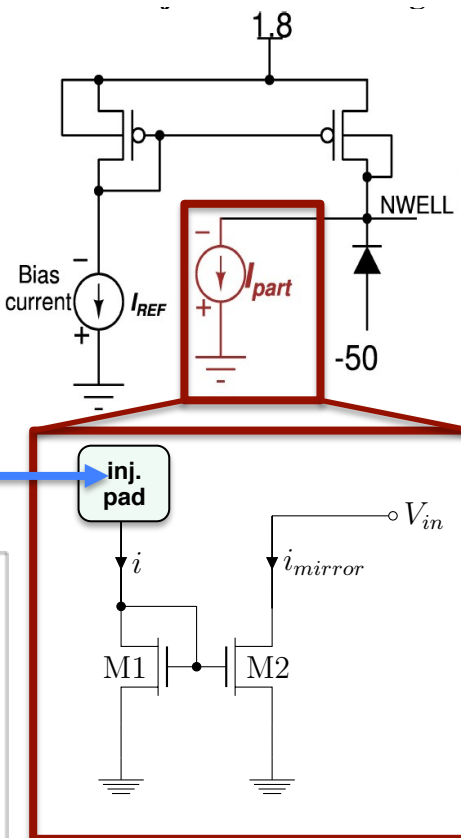
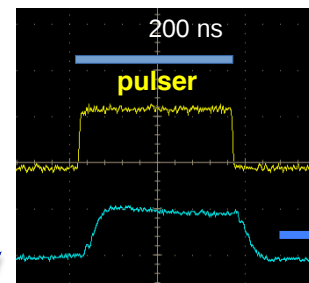
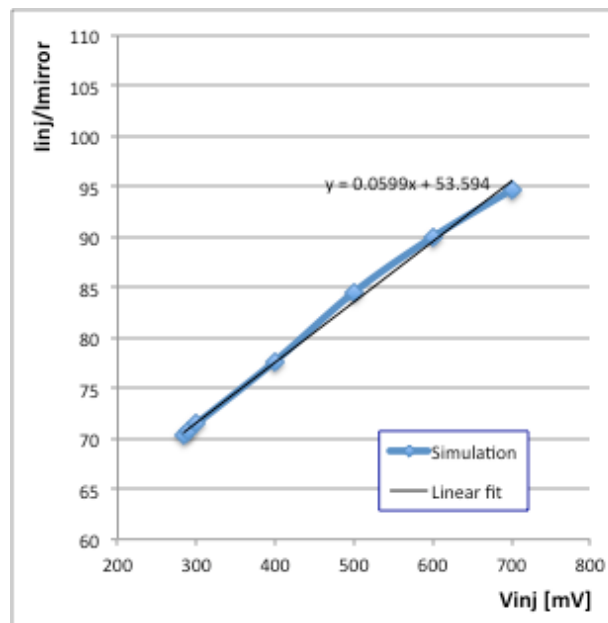
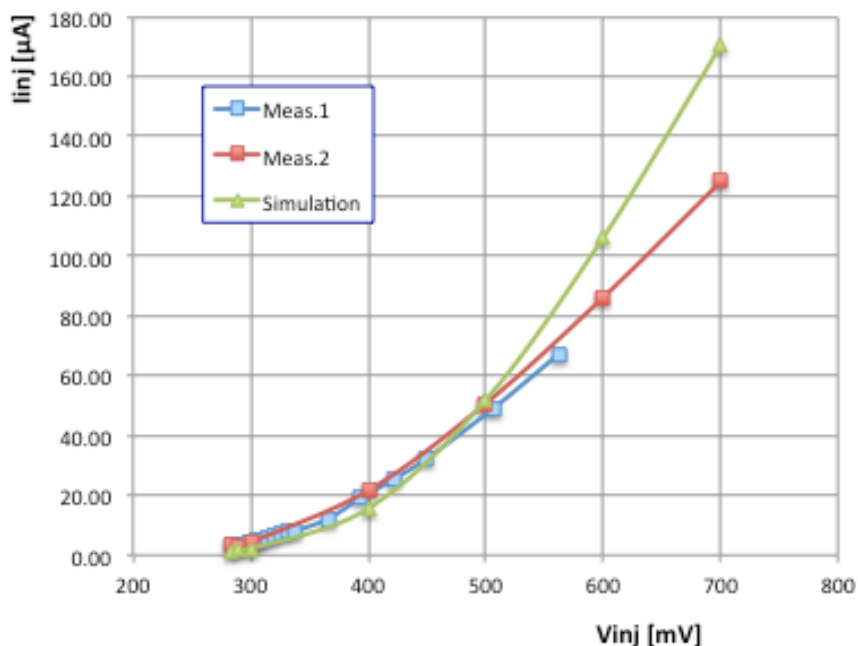
Active pixels: test setup



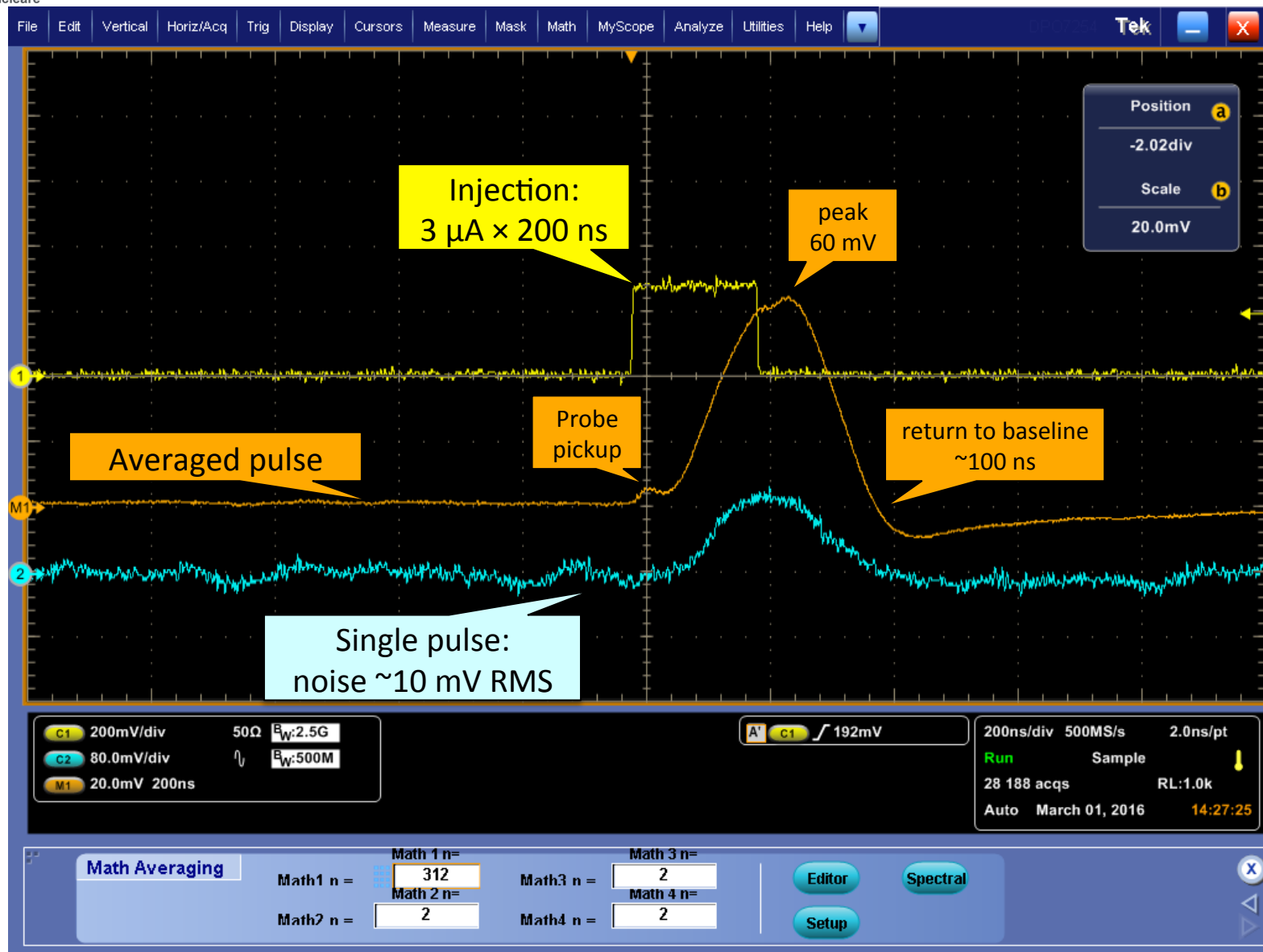
Active pixels: injection

- Injection through a current mirror
 - nominal 1/103 reduction factor
 - operating below saturation: 1/70-1/94
 - not too different from simulation...

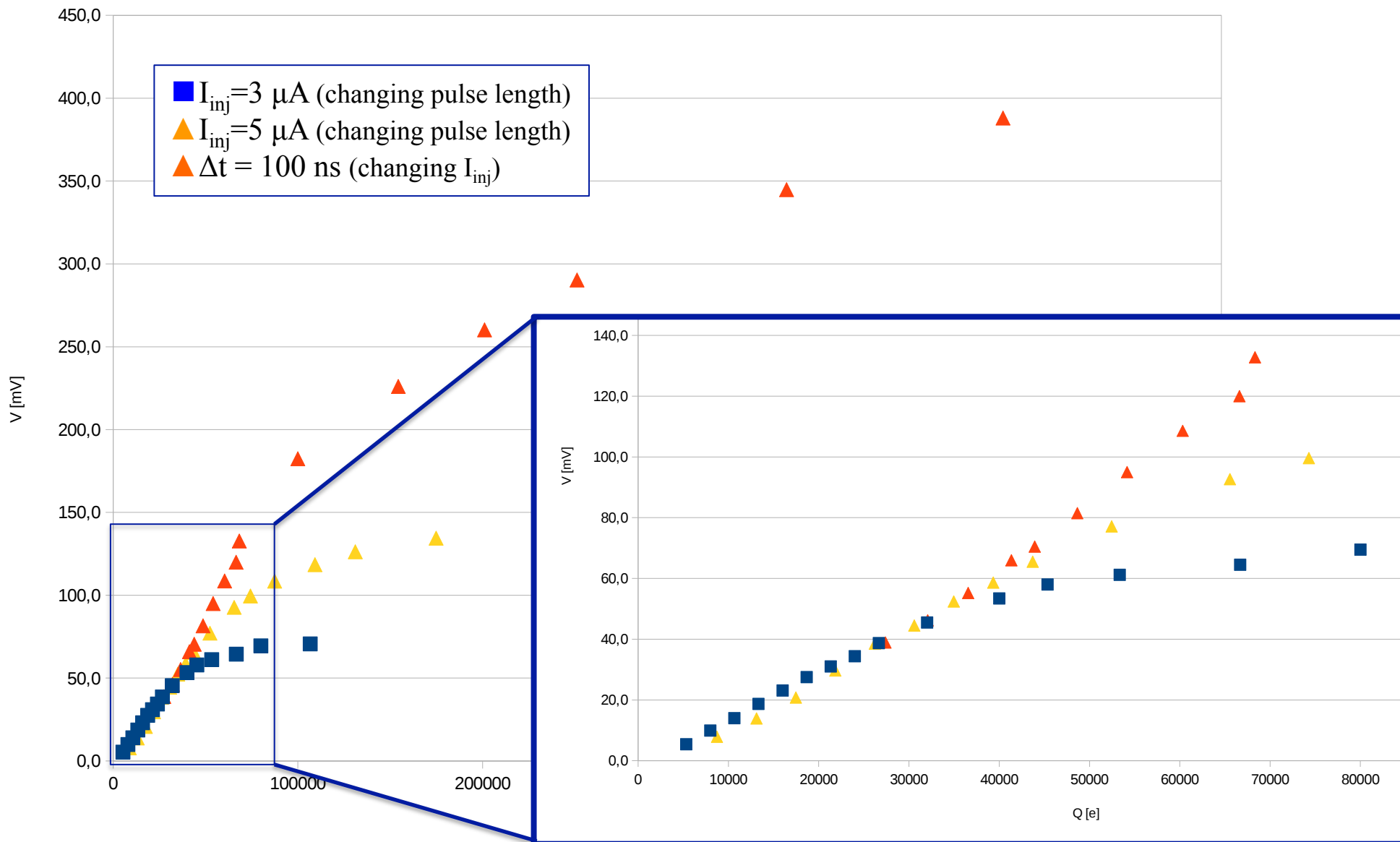
Injection current



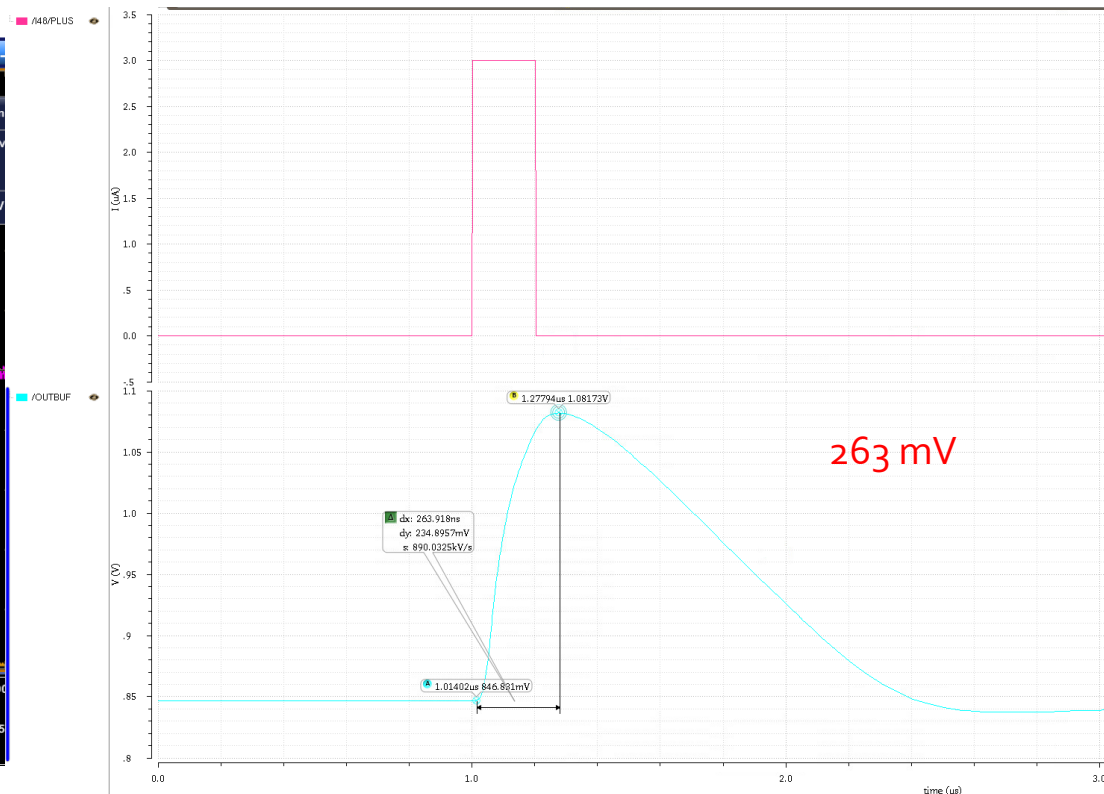
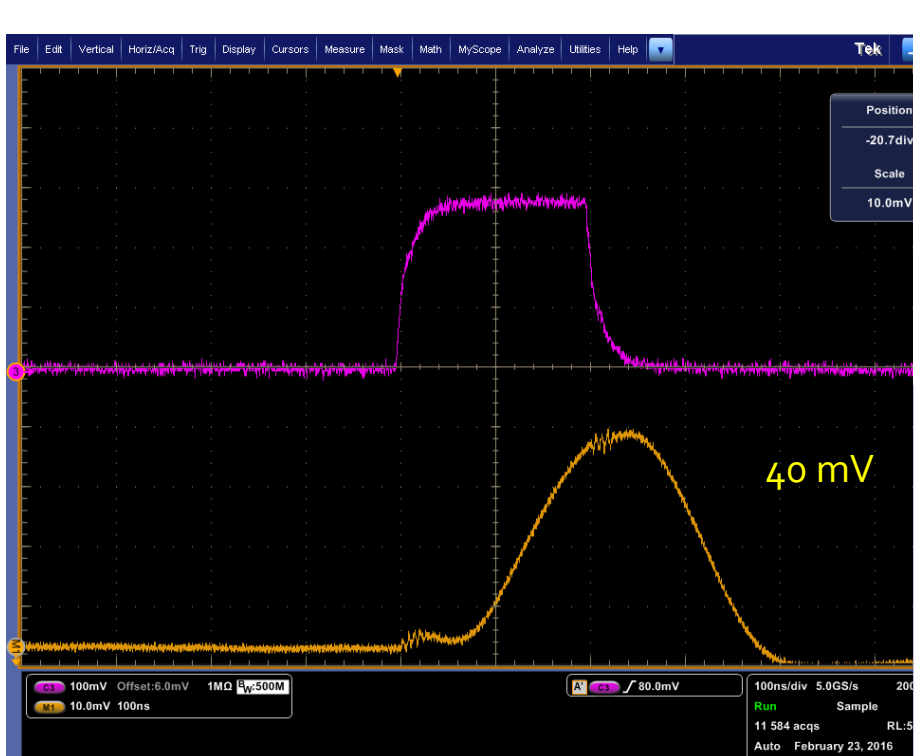
Active pixels: pulse shape



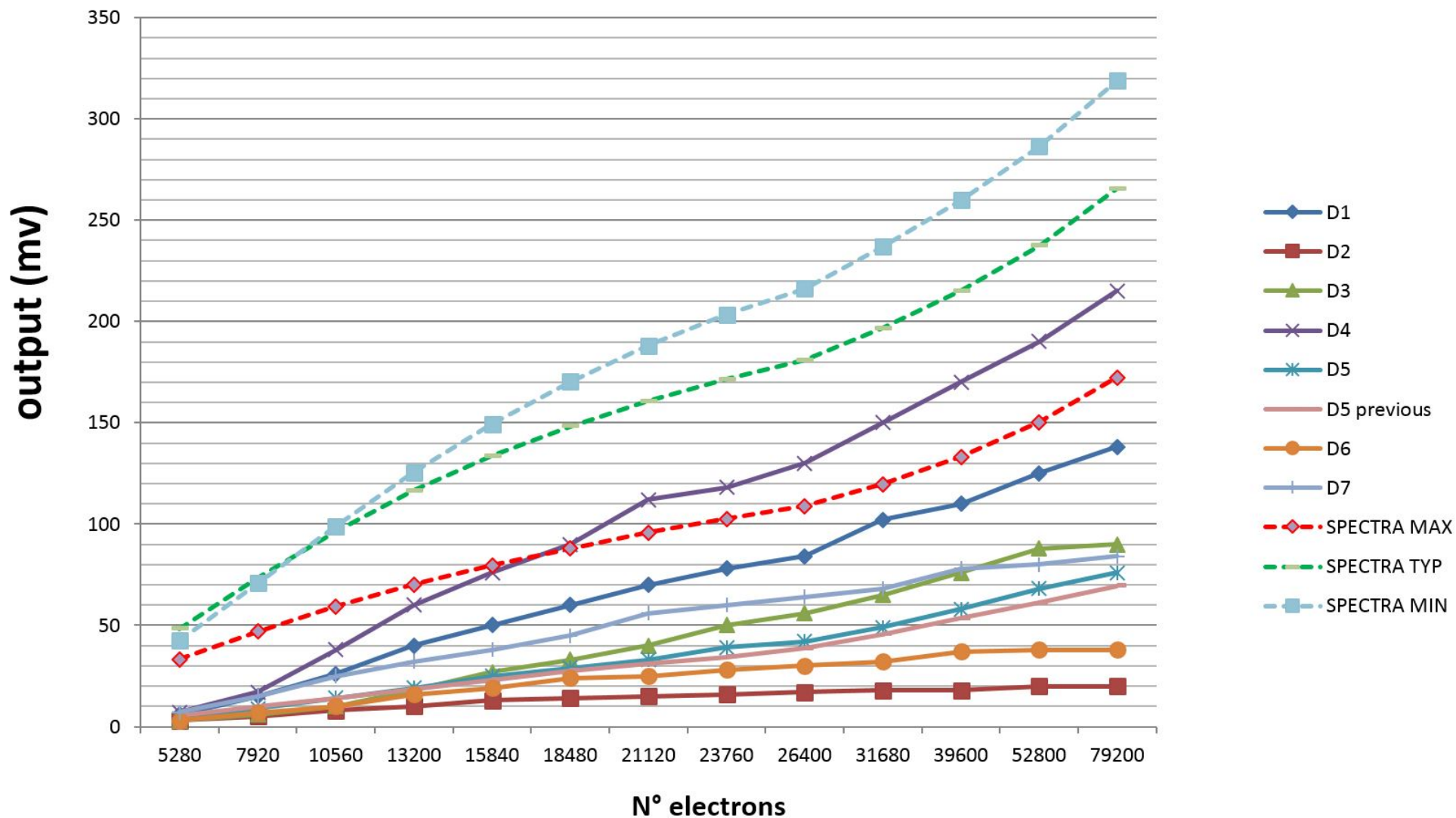
Active pixels: linearity



Active pixels: comparison with simulation



Active pixels: comparison with simulation



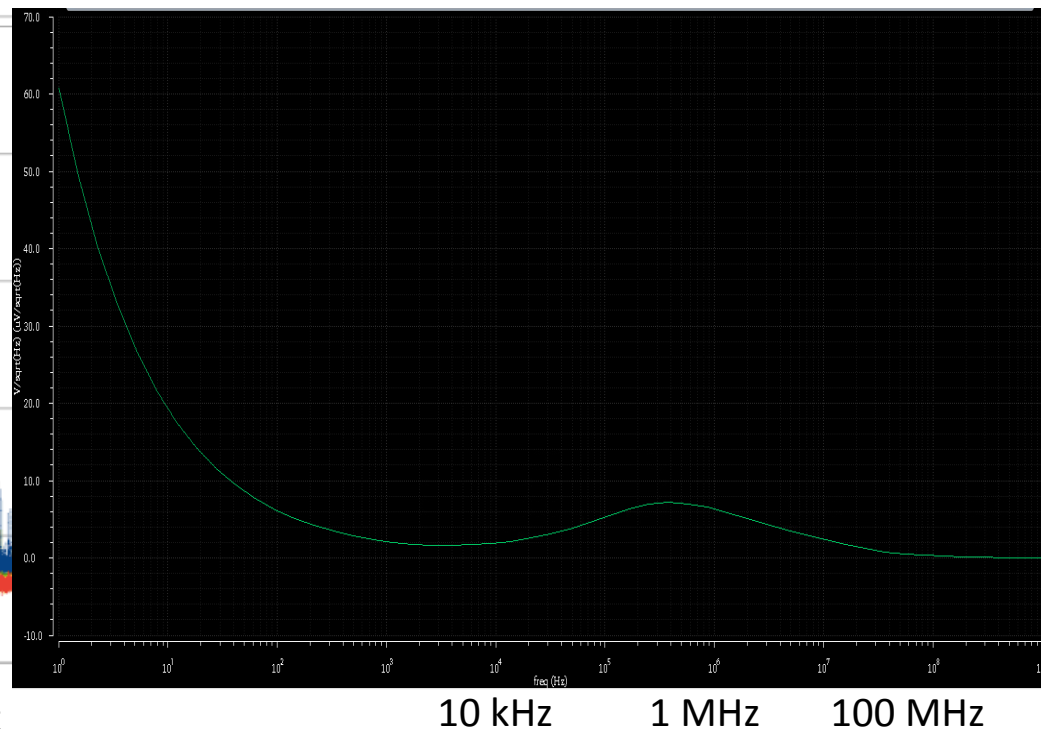
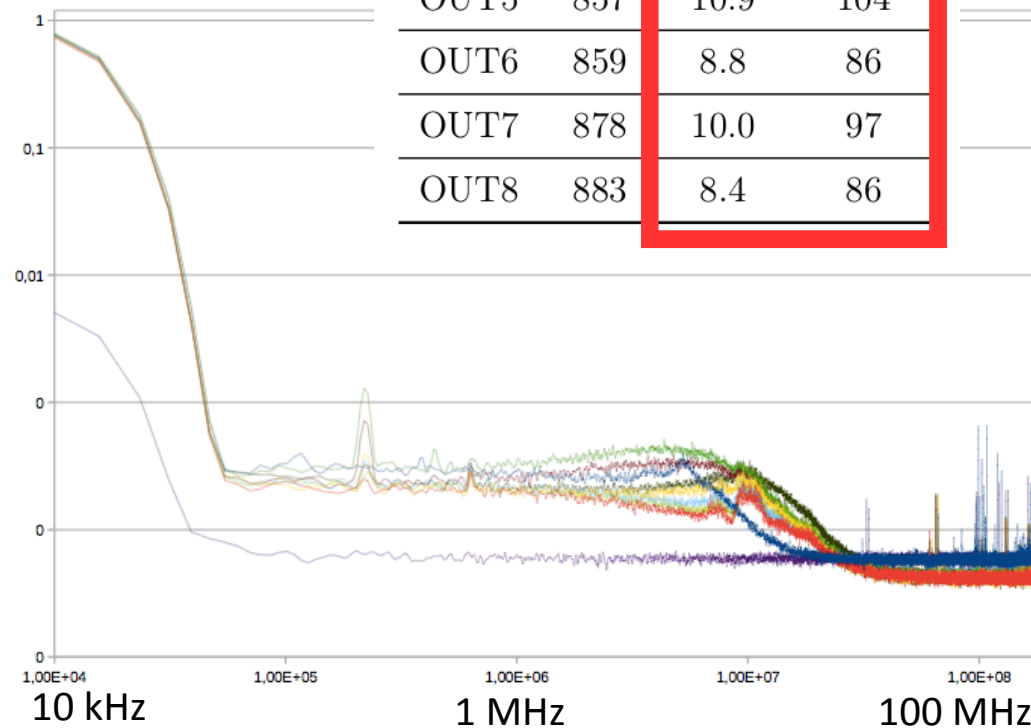
Active pixel: noise

OutBuf Noise (6.6 mV rms)

	DC (mV)	RMS (mV)	PK-PK (mV)
OUT1	847	8.5	102
OUT2	795	8.6	83
OUT3	840	8.9	91
OUT4	855	12.1	116
OUT5	857	10.9	104
OUT6	859	8.8	86
OUT7	878	10.0	97
OUT8	883	8.4	86

Device	Param	Noise Contribution	% Of Total
I8.M4.m1	id	0.00306388	21.02
I0.M17.m1	fn	0.00303263	20.60
I0.M0.m1	fn	0.0027767	17.27

Integrated Noise Summary (in V) Sorted By Noise Contributors
 Total Summarized Noise = 0.00668221
 Total Input Referred Noise = 5.26717e-08
 The above noise summary info is for noise data



- Inspired from demonstrator layout (picture below)
- Lateral space to be tuned to match alignment with FE-I4
- Leftover space at bottom of pixel region is only 20 μm , may be increased in multiple of the 50 μm pixel size.

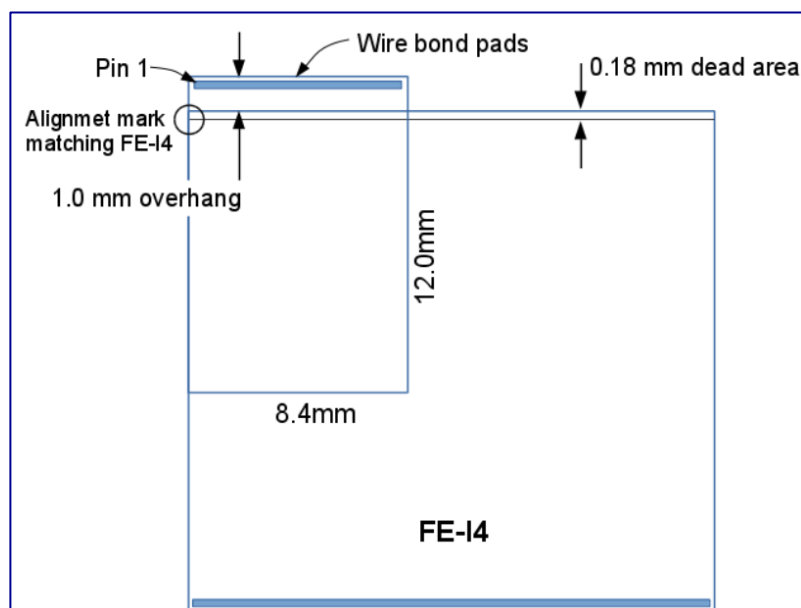
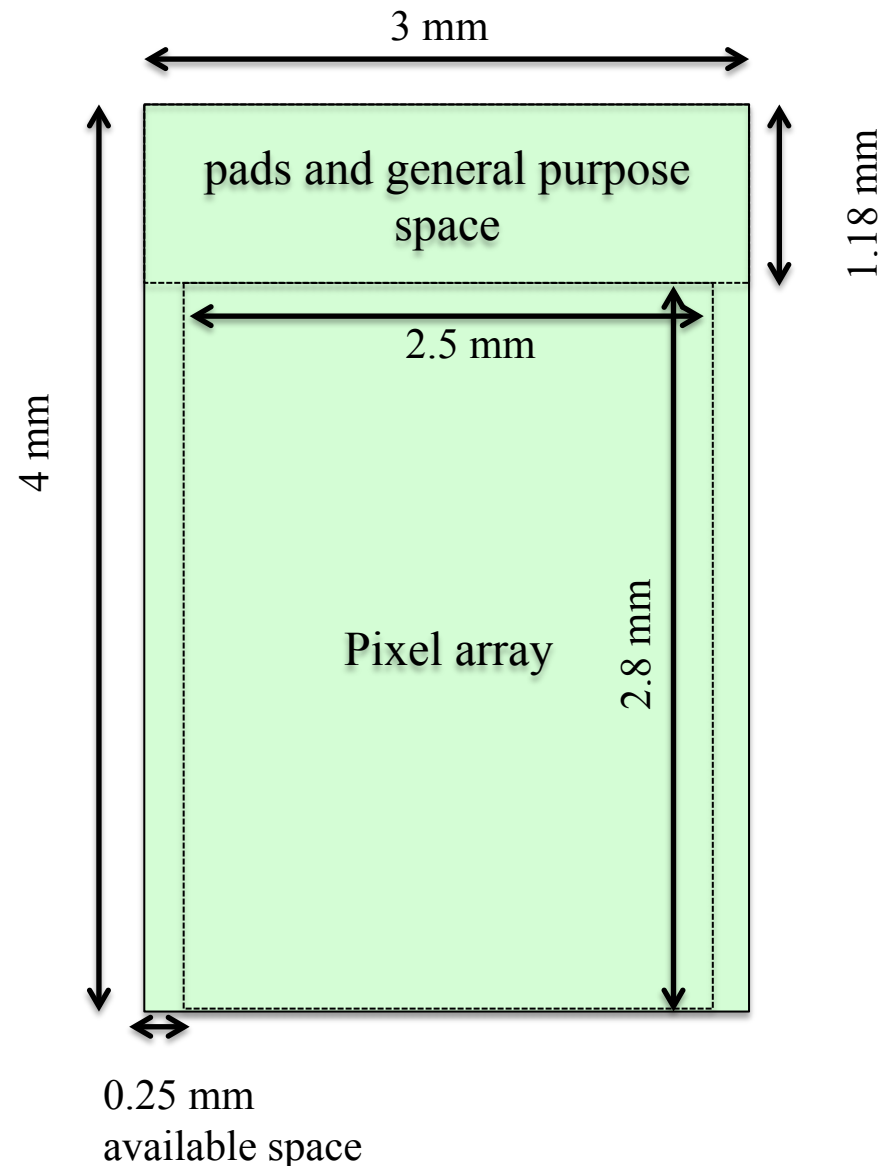
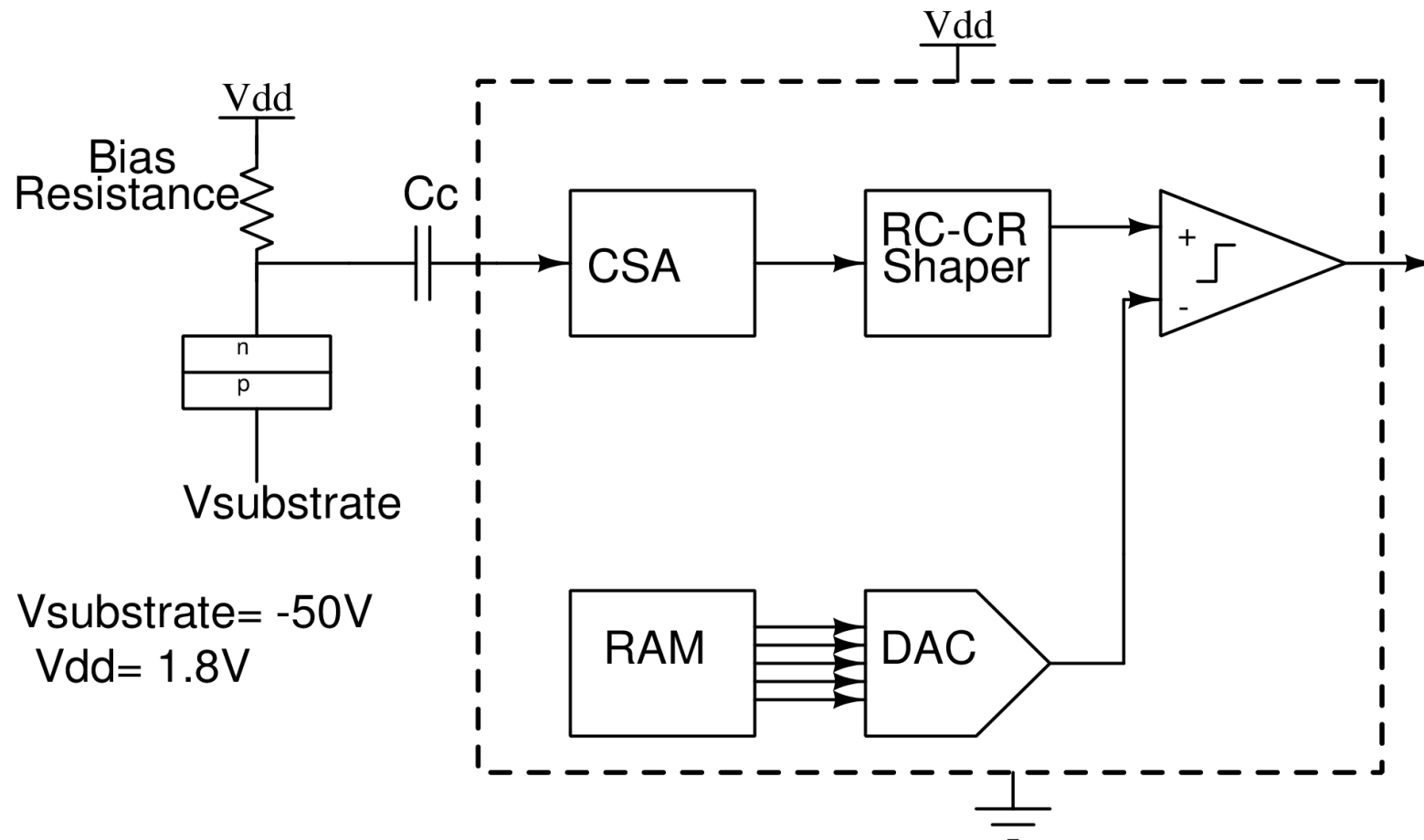


Fig. 1: Alignment of demonstrator to FE-I4 chip



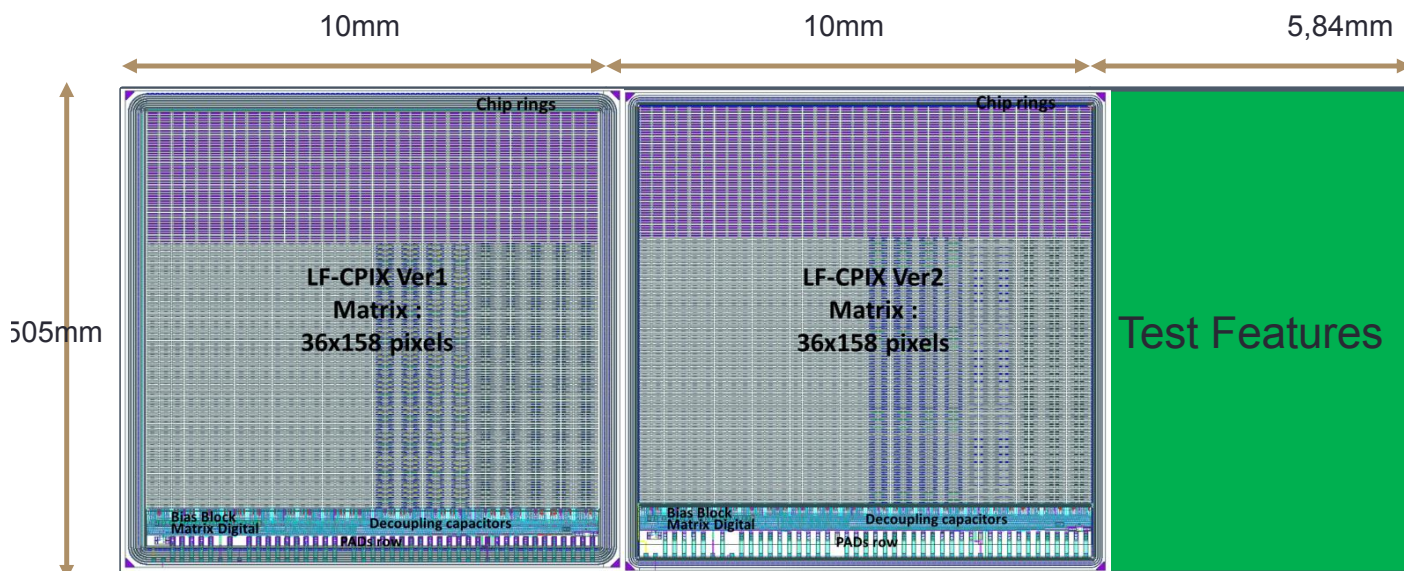


Genova + Mandi + Milano

- Two large size demonstrators:
 - AMS 180 nm (Genève-Karlsruhe), available
 - LFoundry (CPPM-Bonn), submitted

Other technologies being tested:

- XFAB (SOI)
- TowerJazz



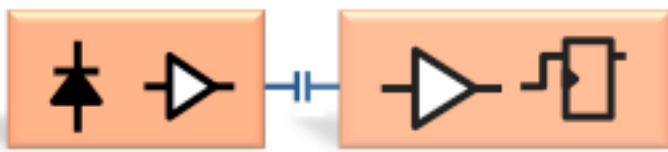
- Seat 1 : LF-CPIX (see details)
- Seat 2 : LF-CPIX with new guards rings strategy
- Seat 3 : test features

Testbeams

		Mon 2 Mai	Tue 3 Mai	Wed 4 Mai	Thu 5 Mai	Fri 6 Mai	Sat 7 Mai	Sun 8 Mai	Mon 9 Mai	Tue 10 Mai	Wed 11 Mai	Thu 12 Mai	Fri 13 Mai	Sat 14 Mai	Sun 15 Mai	Mon 16 Mai	Tue 17 Mai	Wed 18 Mai	Thu 19 Mai	Fri 20 Mai	Sat 21 Mai	Sun 22 Mai	Mon 23 Mai	Tue 24 Mai	Wed 25 Mai	Thu 26 Mai	Fri 27 Mai	Sat 28 Mai	Sun 29 Mai	Mon 30 Mai	Tue 31 Mai	Wed 1 Jun	Thu 2 Jun	Fri 3 Jun	Sat 4 Jun	Sun 5 Jun
	Week	18							19							20							21							22						
Area	T4 - H6	ATLAS AFP H. Kagan							RD42 CMS Outer Tracker D. Lazic							M. Silari							CERF S. Vlachos							ATLAS ITK						
		Mon 30 Mai	Tue 31 Mai	Wed 1 Jun	Thu 2 Jun	Fri 3 Jun	Sat 4 Jun	Sun 5 Jun	Mon 6 Jun	Tue 7 Jun	Wed 8 Jun	Thu 9 Jun	Fri 10 Jun	Sat 11 Jun	Sun 12 Jun	Mon 13 Jun	Tue 14 Jun	Wed 15 Jun	Thu 16 Jun	Fri 17 Jun	Sat 18 Jun	Sun 19 Jun	Mon 20 Jun	Tue 21 Jun	Wed 22 Jun	Thu 23 Jun	Fri 24 Jun	Sat 25 Jun	Sun 26 Jun	Mon 27 Jun	Tue 28 Jun	Wed 29 Jun	Thu 30 Jun	Fri 1 Jul	Sat 2 Jul	Sun 3 Jul
	Week	22							23							24							25							26						
Area	T4 - H6	S. Vlachos							ATLAS ITK S. Vlachos							H. Kagan							RD42 D. Dannheim							Clic pix ATLAS AFP						
		Mon 1 Aug	Tue 2 Aug	Wed 3 Aug	Thu 4 Aug	Fri 5 Aug	Sat 6 Aug	Sun 7 Aug	Mon 8 Aug	Tue 9 Aug	Wed 10 Aug	Thu 11 Aug	Fri 12 Aug	Sat 13 Aug	Sun 14 Aug	Mon 15 Aug	Tue 16 Aug	Wed 17 Aug	Thu 18 Aug	Fri 19 Aug	Sat 20 Aug	Sun 21 Aug	Mon 22 Aug	Tue 23 Aug	Wed 24 Aug	Thu 25 Aug	Fri 26 Aug	Sat 27 Aug	Sun 28 Aug	Mon 29 Aug	Tue 30 Aug	Wed 31 Aug	Thu 1 Sep	Fri 2 Sep	Sat 3 Sep	Sun 4 Sep
	Week	31							32							33							34							35						
Area	T4 - H6	AIDA WP7 S. Vlachos							ATLAS ITK S. Vlachos							D. Dannheim							Clic pix RD42 & Monopix													
		Mon 26 Sep	Tue 27 Sep	Wed 28 Sep	Thu 29 Sep	Fri 30 Sep	Sat 1 Oct	Sun 2 Oct	Mon 3 Oct	Tue 4 Oct	Wed 5 Oct	Thu 6 Oct	Fri 7 Oct	Sat 8 Oct	Sun 9 Oct	Mon 10 Oct	Tue 11 Oct	Wed 12 Oct	Thu 13 Oct	Fri 14 Oct	Sat 15 Oct	Sun 16 Oct	Mon 17 Oct	Tue 18 Oct	Wed 19 Oct	Thu 20 Oct	Fri 21 Oct	Sat 22 Oct	Sun 23 Oct	Mon 24 Oct	Tue 25 Oct	Wed 26 Oct	Thu 27 Oct	Fri 28 Oct	Sat 29 Oct	Sun 30 Oct
	Week	39							40							41							42							43						
Area	T4 - H6	ATLAS AFP D. Lazic							CMS Outer Tracker D. Dannheim							Clic pix V. Manko							ALICE PHOS A. Tauro, S. Vlachos							ATLAS ITK						
		Mon 31 Oct	Tue 1 Nov	Wed 2 Nov	Thu 3 Nov	Fri 4 Nov	Sat 5 Nov	Sun 6 Nov	Mon 7 Nov	Tue 8 Nov	Wed 9 Nov	Thu 10 Nov	Fri 11 Nov	Sat 12 Nov	Sun 13 Nov	Mon 14 Nov	Tue 15 Nov	Wed 16 Nov	Thu 17 Nov	Fri 18 Nov	Sat 19 Nov	Sun 20 Nov	Mon 21 Nov	Tue 22 Nov	Wed 23 Nov	Thu 24 Nov	Fri 25 Nov	Sat 26 Nov	Sun 27 Nov	Mon 28 Nov	Tue 29 Nov	Wed 30 Nov	Thu 1 Dec	Fri 2 Dec	Sat 3 Dec	Sun 4 Dec
	Week	44							45							46							47							48						
Area	T4 - H6	S. Vlachos							ATLAS ITK M. Silari							XSEC																				

- Detected signal from passive diodes
 - still to fully understand depletion depth and rate
 - TCAD / Geant4 simulations (help welcome)
 - trying to organize irradiation tests
(setup in development with Politecnico)
- Fixed KC53AB received:
 - all components are operational
 - gain lower than expected and large dispersion
 - still to understand mismatch between measurements and simulation
- Large pixel matrix to be submitted by mid-April
 - can be matched to FE-I4 chips
 - possibly also to RD53 prototype

ATLAS TCAD workshop
 CPPM, 11-12 May.

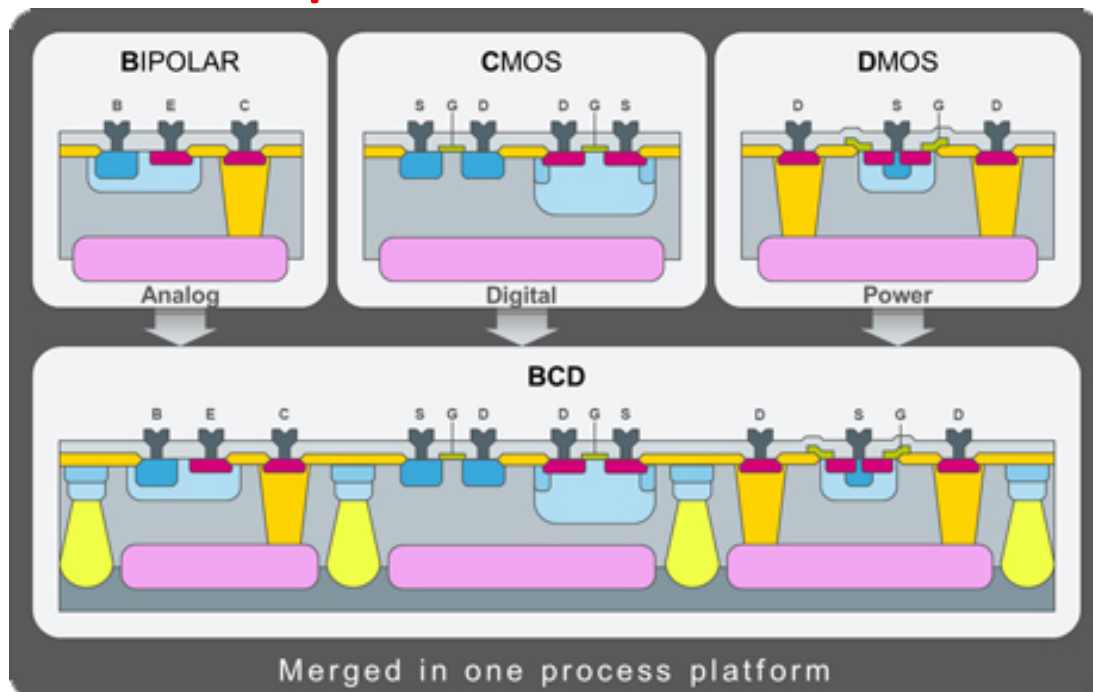


HVR - CCPD

INFN

BACKUP

BCD = Bipolar + CMOS + DMOS



	HIGH DENSITY	HIGH VOLTAGE
0.32μm	BCD6/6s 20/45/70/100V	BCD6s-Offline 800V BCD6s-SOI 100/190V
0.16μm	BCD8/8s 8/20/40/70V	BCD8s-SOI 300V BCD8sP 8/18/25/42V
0.11μm		BCD9s 20/40/65V
90nm		BCD10
Timeline	AVAILABLE	
	IN DEVELOPMENT	

http://www.st.com/web/en/about_st/bcd.html

- Among the competing technologies BCD8 has several appealing features:
 - availability of different devices integrated in the same process
 - epitaxial process**: can easily grow on different substrates.
 - possible to reach thick depletion layers: 30 μm looks an optimal compromise between signal and material thickness of the detector
 - long-term availability**: it is one of the major production line for ST automotive products.

Device	Param	Noise Contribution	% Of Total
M30.m1	fn	0.00689093	26.71
M30.m1	id	0.00646208	23.48
M5.m1	id	0.00420071	9.92
M5.m1	fn	0.0036419	7.46
M41.m1	id	0.00333666	6.26
M41.m1	fn	0.00273693	4.21
M2.m1	fn	0.00238552	3.20
M1.m1	id	0.00235236	3.11
M3.m1	fn	0.0021559	2.61
M21.m1	id	0.00191197	2.06

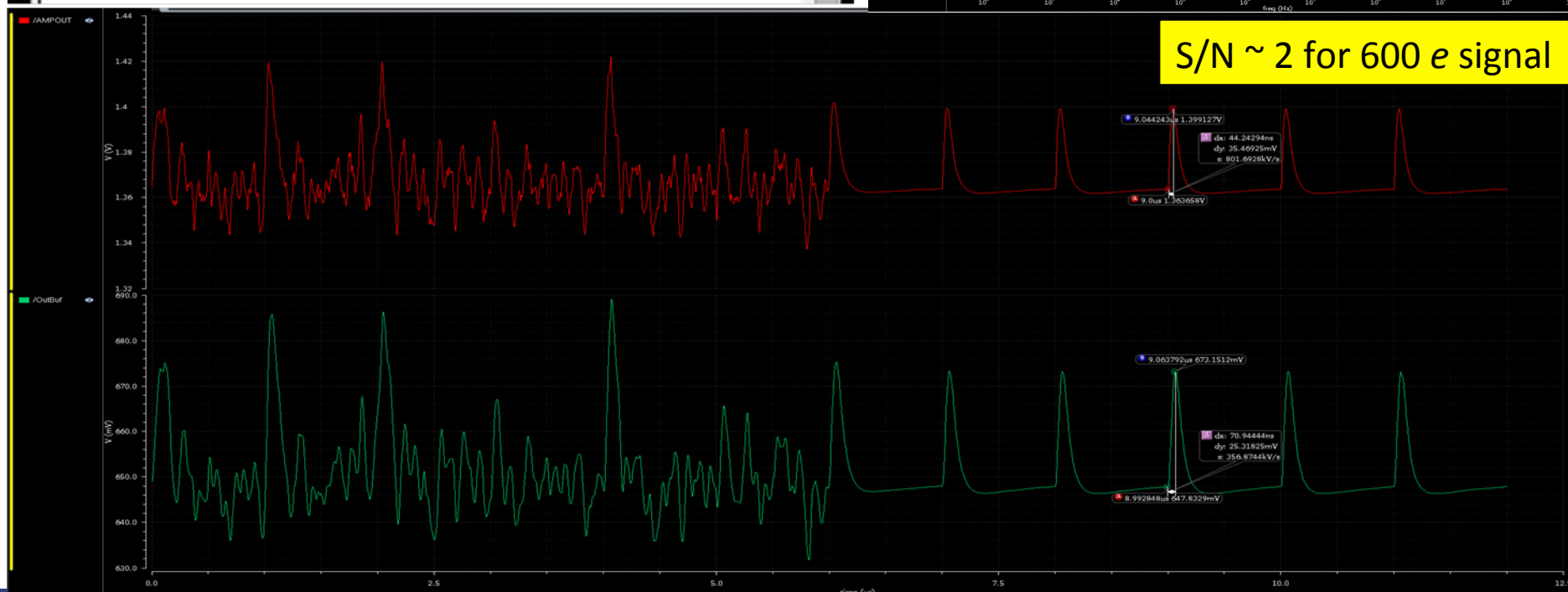
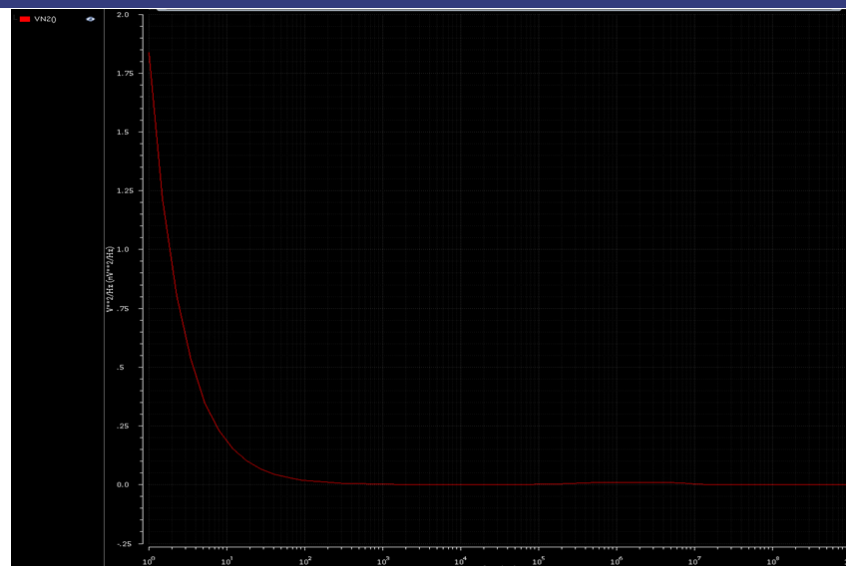
Integrated Noise Summary (in V) Sorted By Noise Contributors

Total Summarized Noise = 0.0133346

Total Input Referred Noise = 0.000239562

line above noise summary info is for noise data


← =239uV ~ VIN



- BCD8 now available also through CMP

- easier to get new people started
- increase of costs with respect to initial informal contacts:


- 2600 Euro/mm²
if Area ≤ 5 mm²
- 13000 Euro
+ [(Area-5) * 2100 Euro]
if 5 mm² < Area < 15 mm²



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Advanced industrial technologies are available in CMOS, SiGe BiCMOS, HV-CMOS, SOI, MEMS, 3D-IC, etc. CMP distributes and supports several CAD software tools for both Industrial Companies and Universities.

Since 1981, more than 1000 Institutions from 71 countries have been served, more than 7275 projects have been prototyped through 952 runs, and 60 different technologies have been interfaced.



cmp

2016

Best wishes
& happy new year

 Meilleurs vœux
& bonne année

MPW runs schedule

	Jan	Feb	Mar	Apr	May	Jun	Jul	Aug	Sep	Oct	Nov	Dec
analog												
C18AA 0.18 µm CMOS												
N18AA 0.18 µm HV-CMOS												
C17HAT 2.0 µm CMOS												
C17HAT1 0.35 µm CMOS Giga												
C18HAT3 0.35 µm CMOS Triax HPA												
H18BAT3 0.35 µm HV-CMOS												
S17CAH1 0.35 µm SiGe												
SiMicroelectronics												
CH02IMP050 28 nm SOI												
BICH05G55 55 nm BiCMOS												
CH05G65 65 nm CMOS												
HCH05RGP 130 nm CMOS												
HCH05RA 130 nm BiCMOS												
BICH05RW 130 nm SiGe												
HPSOC-FEM 130 nm SOI												
BC05RP 180 nm BiO												
MEMSICAP												
PUMP1 2.0 µm poly/pumps												
PIASUPUMPS 3.0 µm PIASUPUMPS												
PUMP1 3.0 µm BICOPLUMPS												
PUMP1 6.0 µm micropumps												
CEA LETI Open 3D												
CH02IMP050 28 nm SOI 3D												
BICH05RA 55 nm SOI 3D												
CH05G65 65 nm CMOS 3D												
HCH05RGP 130 nm CMOS 3D												
BICH05RW 130 nm SiGe 3D												
C18HAT3 0.35 µm CMOS 3D												

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